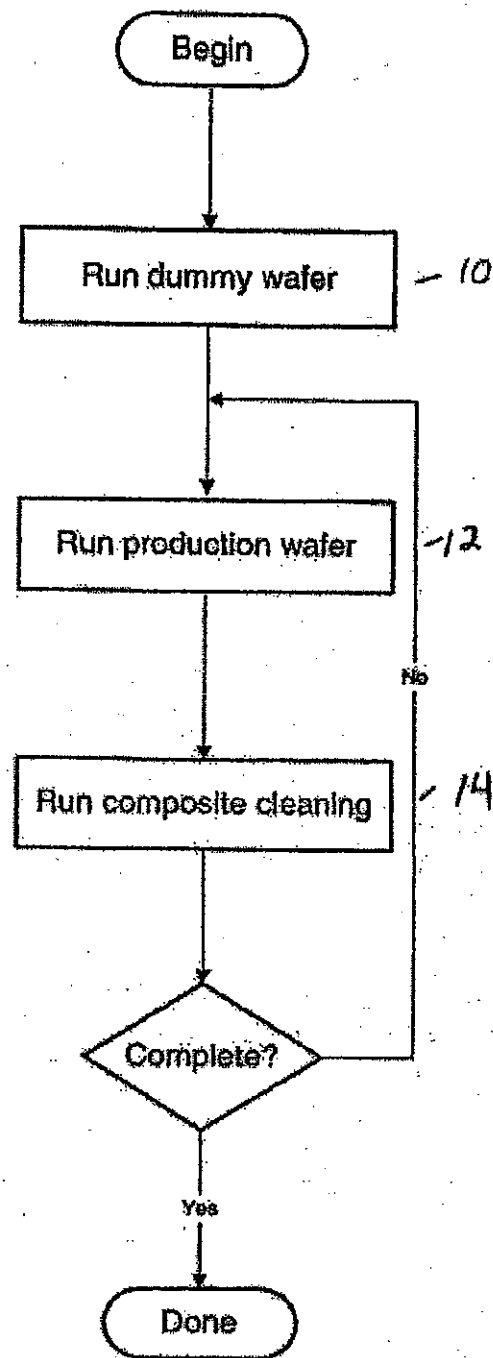


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**Fig. 1 (prior art)**

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plasma etching
→ 100 system

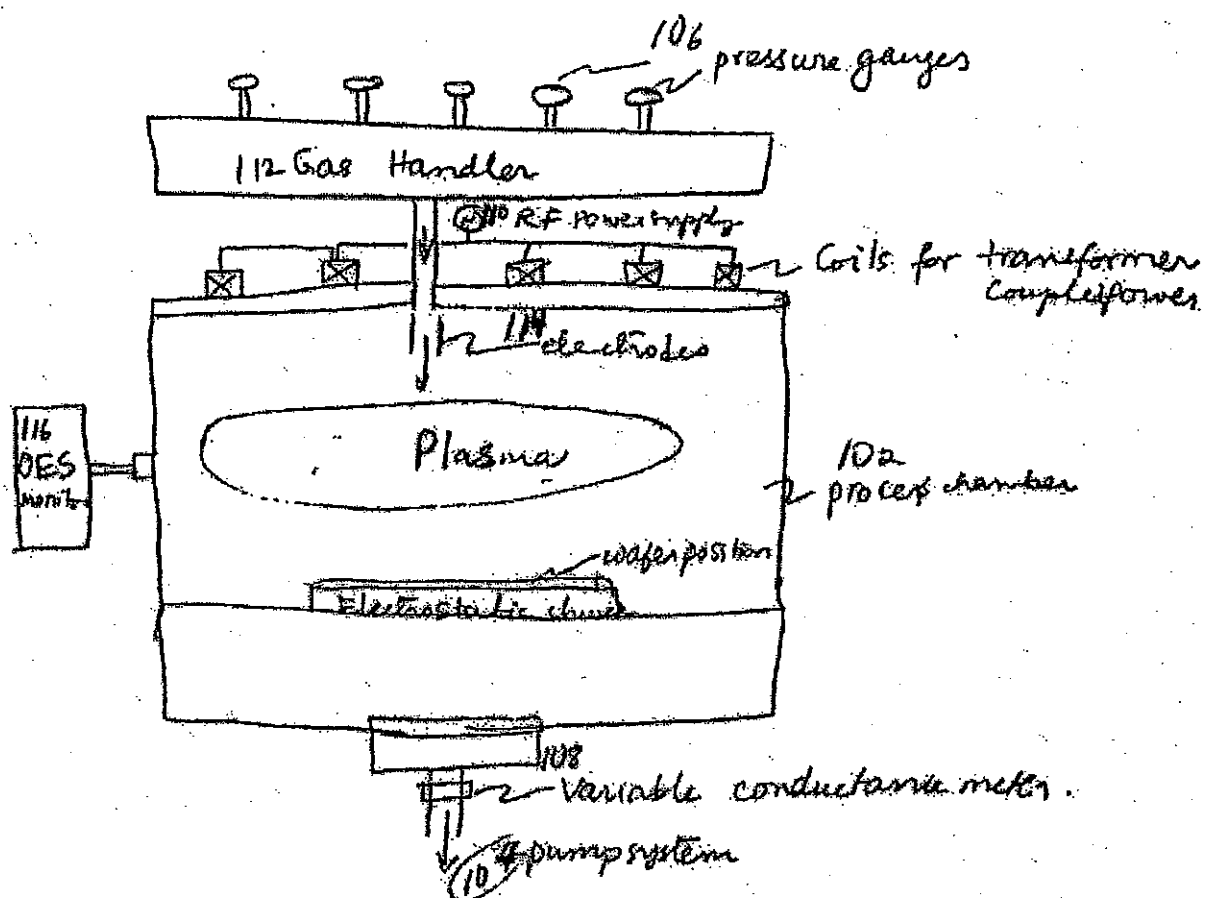


FIG. 2

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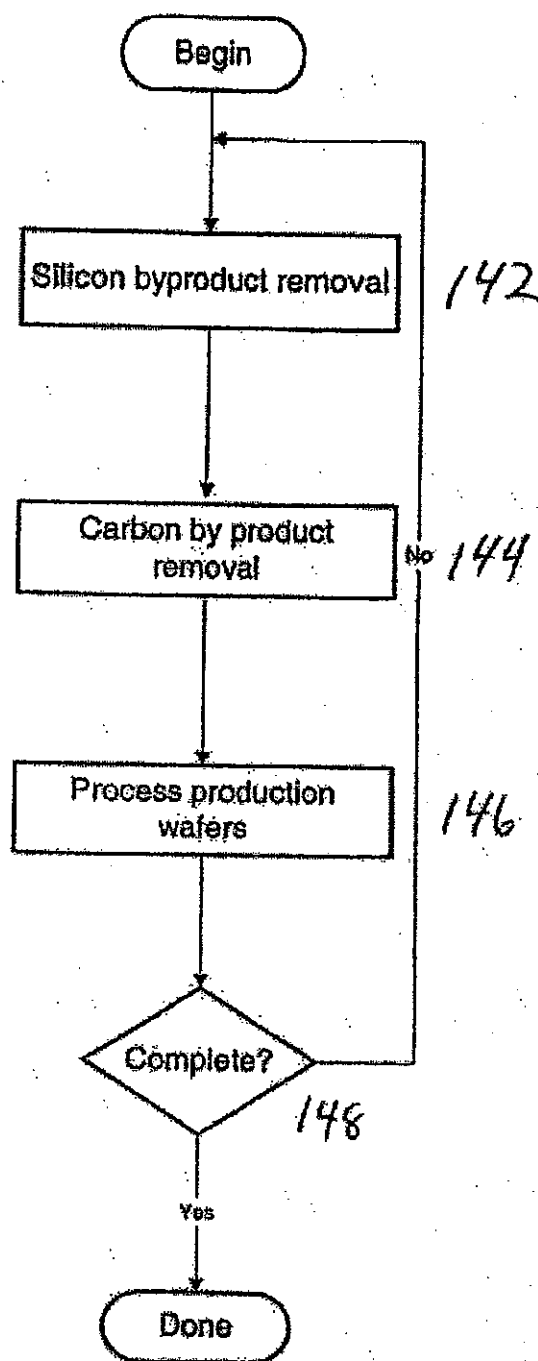


Fig. 3

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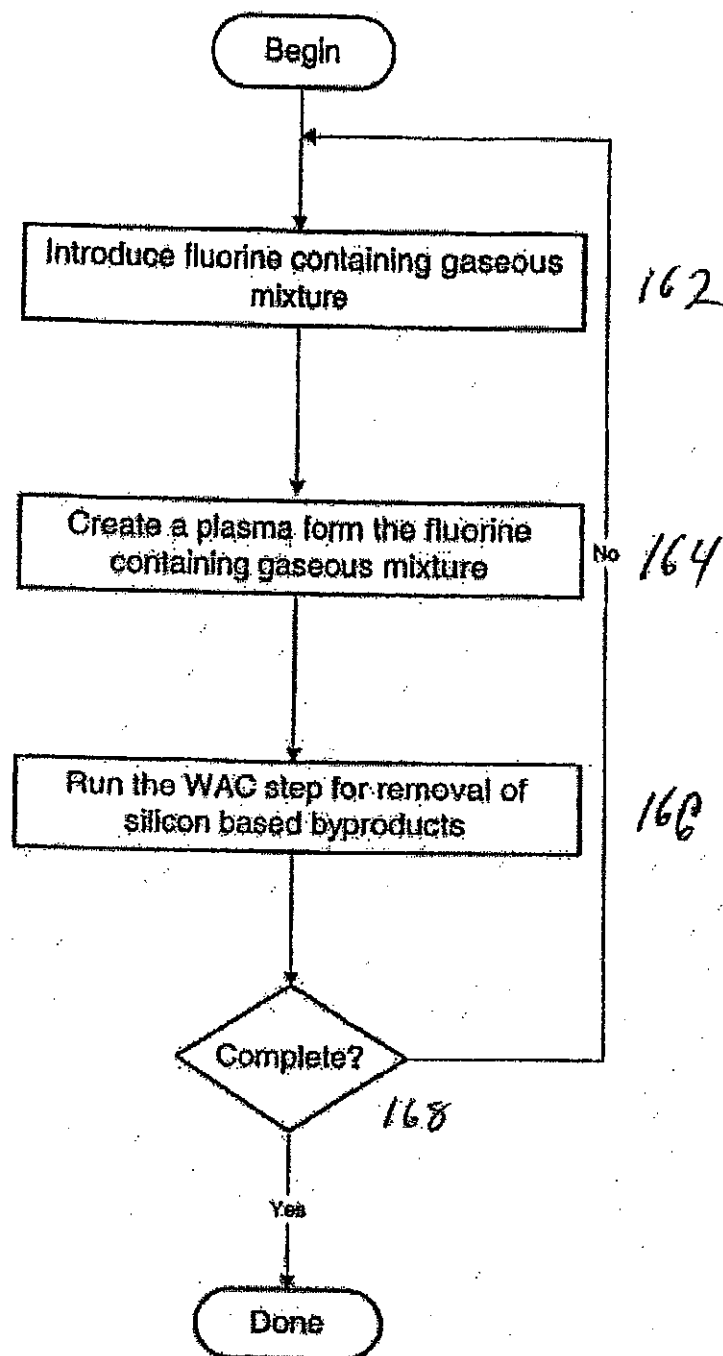


Fig. 4

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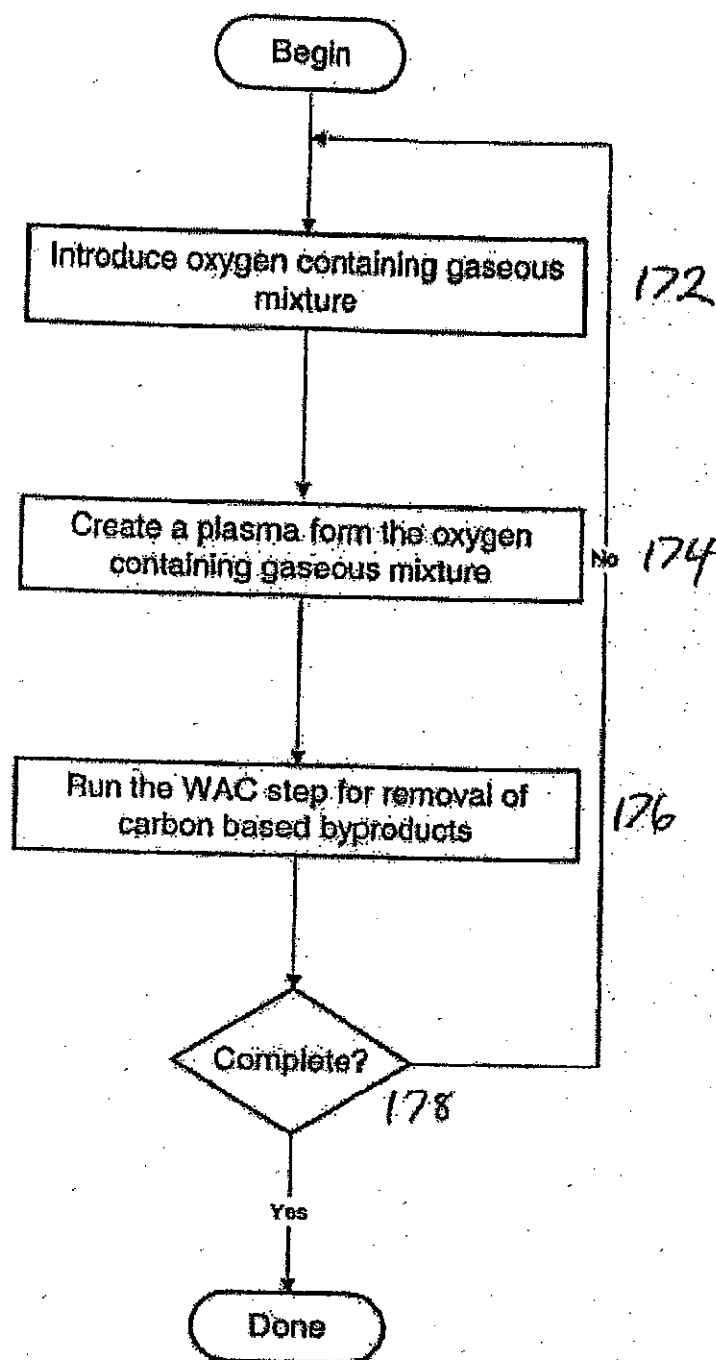


Fig. 5

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Figure 10. Effect of WAC on Etchrate Performance

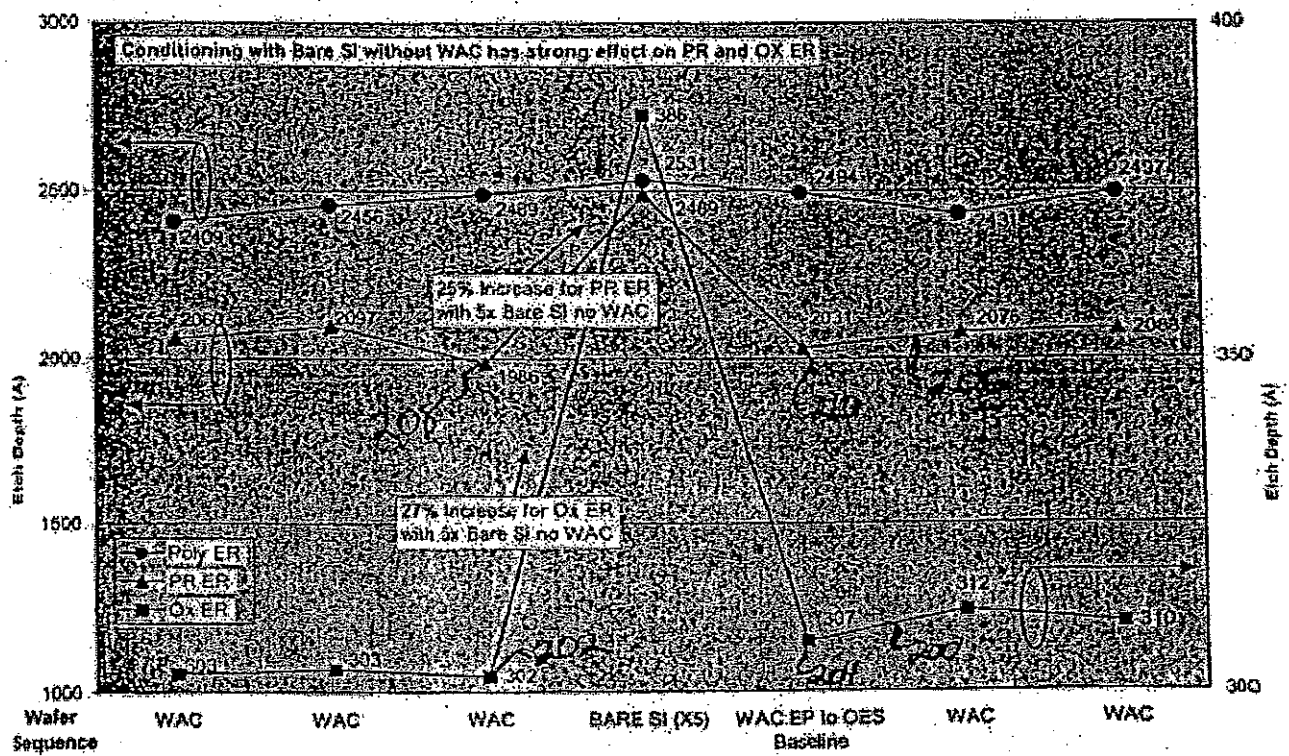


Fig 6

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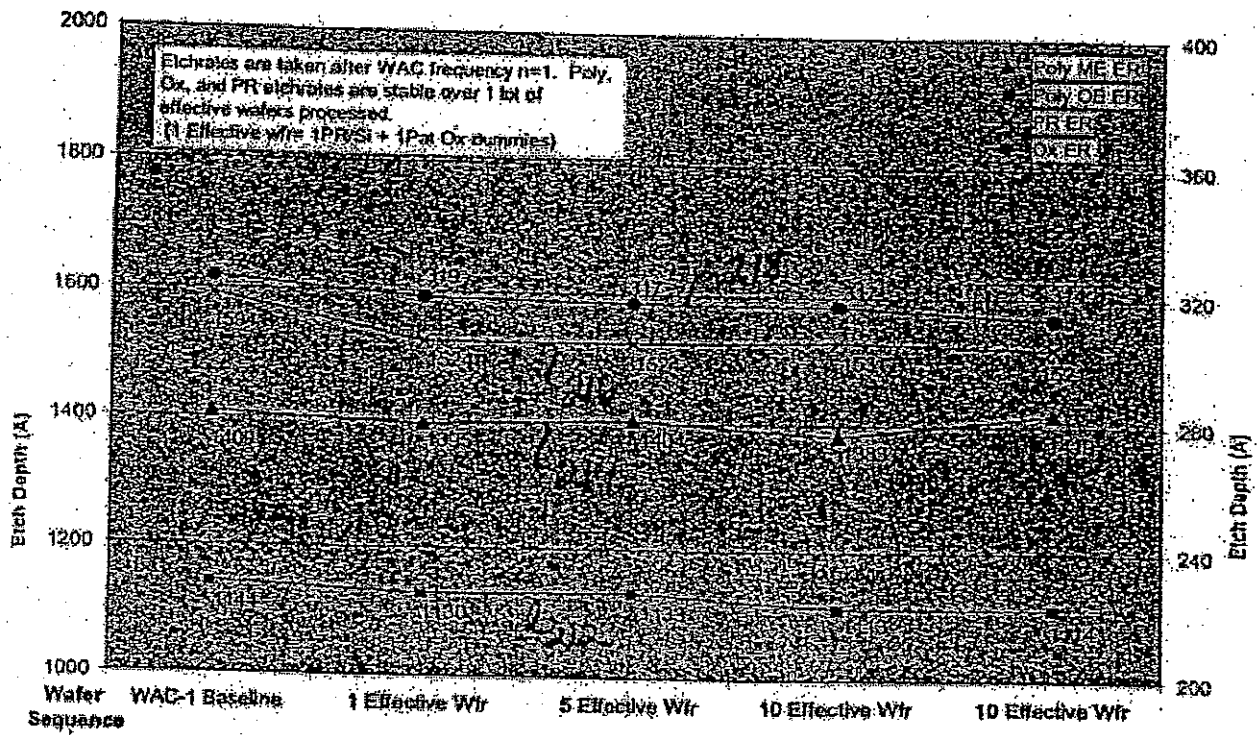


Fig. 7